

10/550509

Docket No.: HEI-010

JC20 Rec'd PCT/PTO 22 SEP 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Hideo KURASHIMA et al.

U.S. Patent Application No.: -----

Filed: *herewith*

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Confirmation No.

Group Art Unit: -----

For: MICROWAVE PLASMA PROCESSING METHOD

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Preliminary to examination of the above-referenced application, please amend the application as follows:

**Amendments To The Claims** begins on page 2 of this paper.

**Remarks** begins on page 6 of this paper.